



DYNAMIC SOLUTIONS THE LINK TO BRIDGING CONCEPTS



M 300
MILESTONE

FOUP/FOSB/RSP-CLEANING SYSTEM

HIGH THROUGHPUT

LOW CoD

HIGHEST FLEXIBILITY 6"/8"/12"

SEMI-AUTOMATED TOOL

M 300 Milestone

Centrifugal Force Cleaner



Dynamic Micro Systems



東横化学株式会社
TOYOKO KAGAKU CO., LTD.

Semiconductor Equipment GmbH

Im Wiesengrund 17 · 78315 Radolfzell-Germany
Tel. ++49-7732-9409-0 · Fax ++49-7732-9409-200
www.dms-semi.de · e-mail: marketing@dms-semi.de

Performance

Short cycle time

Superior wash & rinse

Excellent IR-drying

Throughput:

14 - 32 cassettes / boxes per hour

M 300 Milestone



CENTRIFUGAL FORCE CLEANER

Features

Product flexibility

RSP / FOUP / FOSB / open cassettes

ESD and humidity control

Special DI water treatment

S2 / S8 certified

Insert Systems for FOUP/FOSB/RSP



Software Features

Easy to use Windows® based touch screen user interface
Flexible cleaner recipe editor,
History and error log files for quick diagnostics

SECS / GEM Host interface
(SEMI E4, E5, E30, E37) or
SEMI compliant 300 mm Host
interface (SEMI E4, E5, E30,
E37, E39, E40, E87, E94)

Special DI water spray nozzle
design for better coverage

Adjustable for dirty spots



Options

Carrier management

BC and RF-tag reader

Insert identification

DI-water heater

FM 4910 material

High pressure DI water rinse



Facility Requirements

1280 x 1280 x 2650 mm (WDH)

Weight: 1000 kg

Power: 208 - 480 VAC, 50/60 Hz

for more information please contact DMS direct

Dynamic Micro Systems



東横化学株式会社
TOYOKO KAGAKU CO., LTD.

Semiconductor Equipment GmbH

Im Wiesengrund 17 · 78315 Radolfzell-Germany
Tel. ++49-7732-9409-0 · Fax ++49-7732-9409-200
www.dms-semi.de · e-mail: marketing@dms-semi.de